

(A) JPN

AMENDMENT UNDER 37 CFR 1.116 EXPEDITED
PROCEDURE – EXAMINING GROUP 2823



PATENT
Attorney Docket No.: A7695/T51600
AMAT No.: 007695 USA/DSM/PMD/JW
TTC No.: 016301-051600US

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

WON B. BANG et al.

Application No.: 10/712,464

Filed: November 12, 2003

For: RAMP TEMPERATURE
TECHNIQUES FOR IMPROVED
MEAN WAFER BEFORE
CLEAN

Confirmation No. 9288

Examiner: William D. Coleman

Technology Center/Art Unit: 2823

**AMENDMENT UNDER 37 CFR 1.116
EXPEDITED PROCEDURE EXAMINING
GROUP 2823**

PL 6/28/05
Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Final Office Action mailed August 22, 2005 on the above-referenced application, please enter the following amendments and remarks:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 11 of this paper.

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